Wafer Thickness Measuring Instruments



Dedicated Air Servo Type Wafer Thickness Measuring System Wafer Thickness Measuring Instrument (Patent Pending)

■ Features

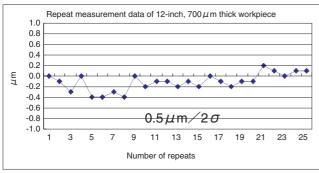
- Non-contact measurement using air
- •Can measure glass other than wafers (must be more than 700 μ m thick)
- Wafer-only measurement part available as an option
- Measuring range: 8.5 mm long stroke

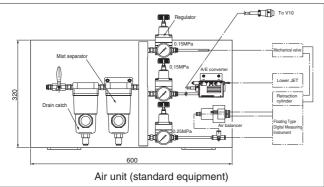


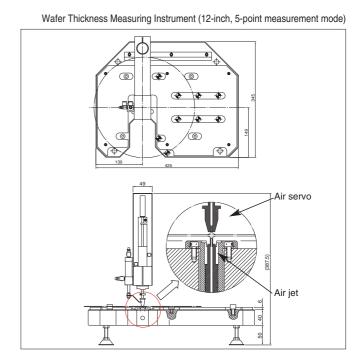
Photograph shows 3" to 8" center 1-pointer measurement mode.

Features

- ① Measurement using manual movement between one center point and four perimeter points.
- ② Measurement data can be sent to a PC (option).
- 3 Easy switching to 8-inch setup by changing a pin position







Specifications			
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Repeatability	1 μ m max./2 σ		
Detector (upper)	Air servo type		
Detector (lower)	Air jet		
Measuring range, detector (upper)	8.5mm		
Measuring range, detector (Lower)	0.04mm		
Supported wafer diameters	8 and 12 inches, manual setup change		
Measurement points	Center, four perimeter points		
Perimeter measurement	4mm from edge		
Display unit	PULCOM V10 + Counter board		
Air pressure	0.3 MPa min.		
Operating temperature	10 to 40°C		
Accuracy guaranteed temperature	±1°C max. during master setting		
Power source	AC 85 V - 250 V max., 50/60 Hz, 50VA		

Product Codes	Product name	Specifications	Remarks
4295154	Air Servo Wafer Thickness Measuring Instrument	3" to 8", 1-point center measurement	Servo nozzle; measurement stand; V10A; air unit; A/E converter
4295155	Air Servo Wafer Thickness Measuring Instrument	8" and 12", center and perimeter measurement	Servo nozzle; measurement stand; V10A; air unit; A/E converter
4295156	Master for above	For ZERO/CAL	
	Option		
4295157	Auto judgment function		Judgment results are output when measurement values stabilize.
0930106	RS-232C output		Requires input of an external judgment start signal or auto judgment function.
0930108	Data link software		Requires input of an external judgment start signal or auto judgment function.
0930137	Printer (Japan model)		Requires input of an external judgment start signal or auto judgment function.